



PATENT  
Docket No. 844,004-263  
(Former docket no. 269/132)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of:

Eric PROPHET

Serial No.: 10/072,656

Filed: February 7, 2002

For: STICKTION ALLEVIATION USING  
PASSIVATION LAYER  
PATTERNING

Group Art Unit: 2811

#8/a  
Examiner: Loke, Steven Ho Yin  
2-21-03

RECEIVED  
JAN 31 2003  
TECHNOLOGY CENTER 2800  
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AMENDMENT AND RESPONSE

BOX AMENDMENT

Assistant Commissioner for Patents  
Washington, D.C. 20231

Sir:

In response to the Office Action mailed on January 3, 2003, Applicant submits the following amendments and remarks.

In the Specification

Please delete the first paragraph on page 6 of the specification and insert the following replacement paragraph:

a  
--Referring to Figure 2, a variable MEMS capacitor according to an embodiment of the invention is shown. The MEMS capacitor is similar to the MEMS structure in Figure 1, but further comprises a bottom electrode 115 on the substrate 15 and

CERTIFICATE OF MAILING (37 C.F.R. §1.8)

I hereby certify that this paper (along with any referred to as being attached or enclosed) is being deposited with the United States Postal Service on the date shown below with sufficient postage as First Class Mail in an envelope addressed to the Commissioner for Patents, Washington, D.C. 20231.

Date of Deposit

1/29/03

Denise N. Doss